

Update on noise studies with a CsI(Tl) crystal

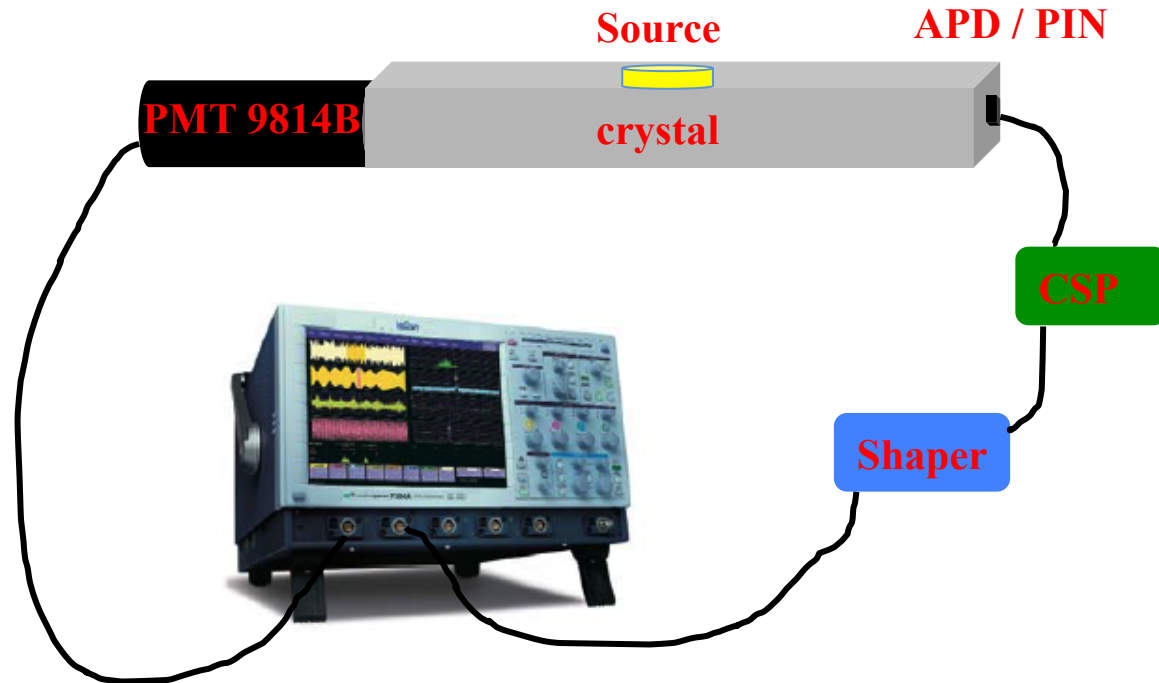
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La Biodola – 2/6/2012

Experimental setup

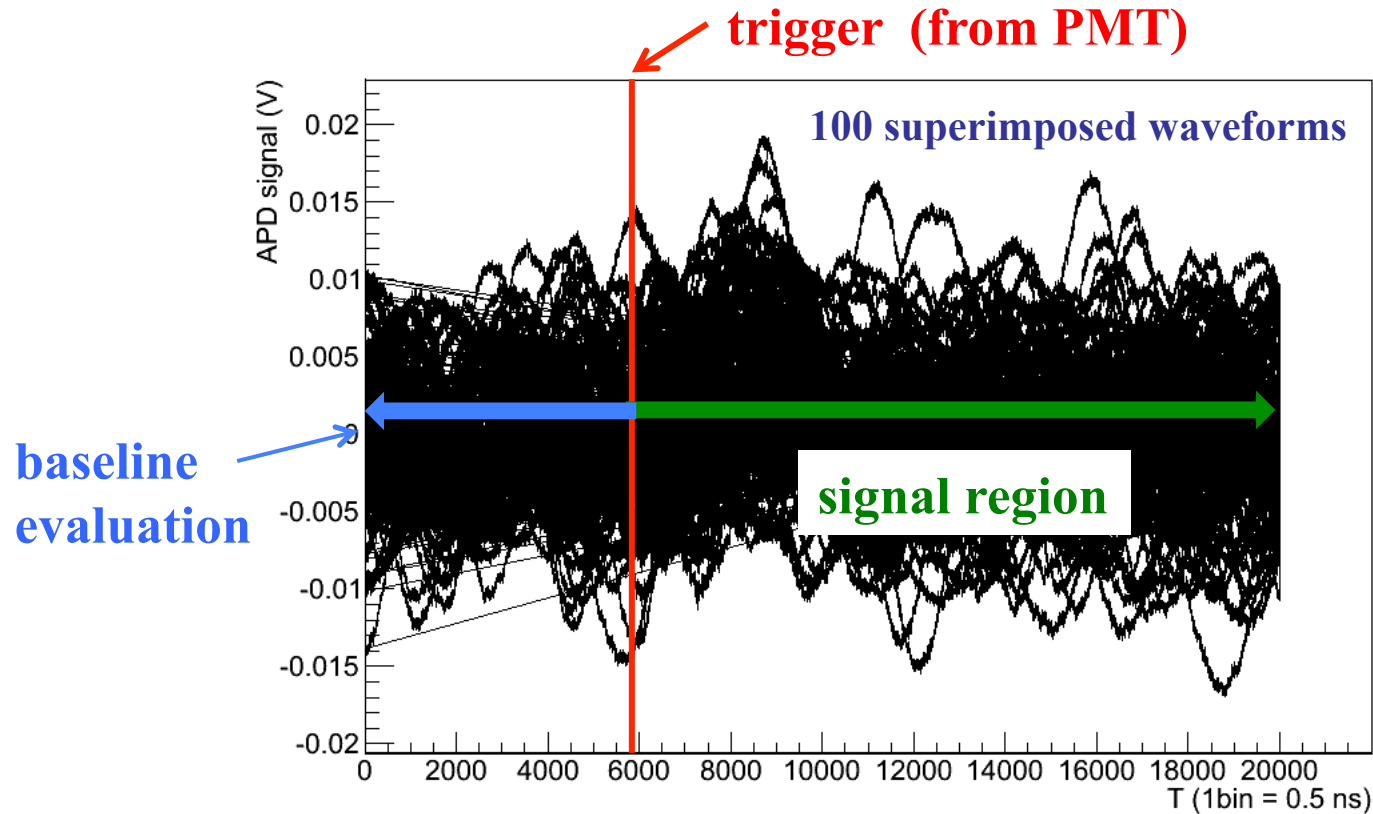
- Aims of this test: evaluate the electronic noise as a function of the FEE integration time and shaping time
- Crystal readout on one side by either an APD or a PIN diode followed by a charge amplifier (CSP) and by a shaper
- PMT on the other side for trigger

- Crystal under test:
 - CsI(Tl) (BaBar)
 - $\sim 6 \times 6 \times 30 \text{ cm}^3$
- Source: ^{60}Co
 - $\Rightarrow \gamma: 1.17 \text{ MeV}$
 - 1.33 MeV



Signal evaluation

- Events acquired by a LeCroy digital oscilloscope (12 bits)
- Waveforms recorded at a sampling rate of 20GS/s
50000 events / measurement

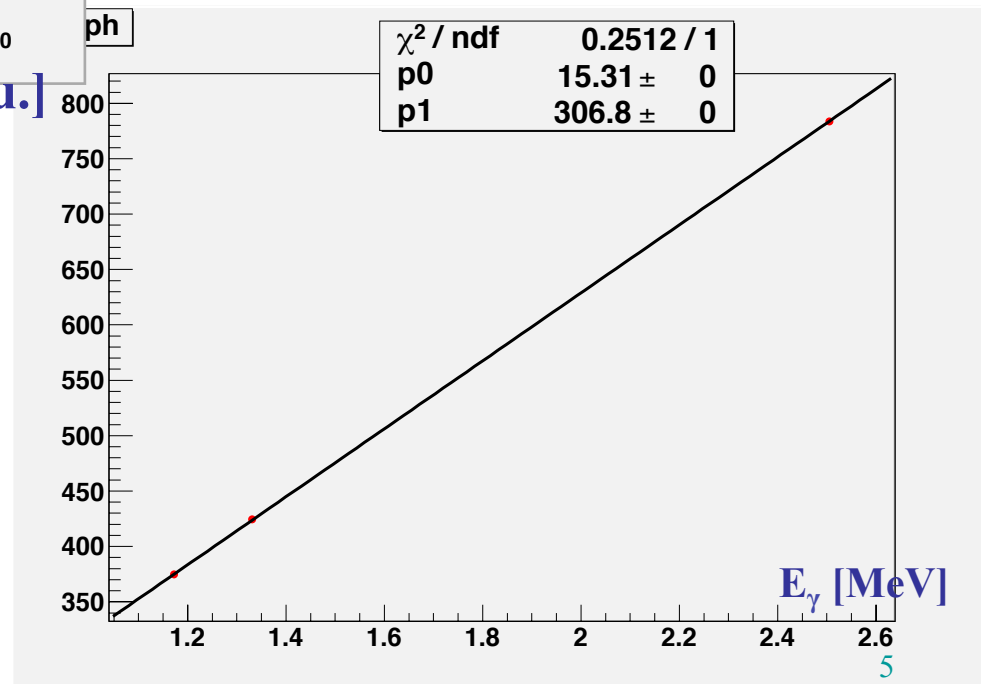
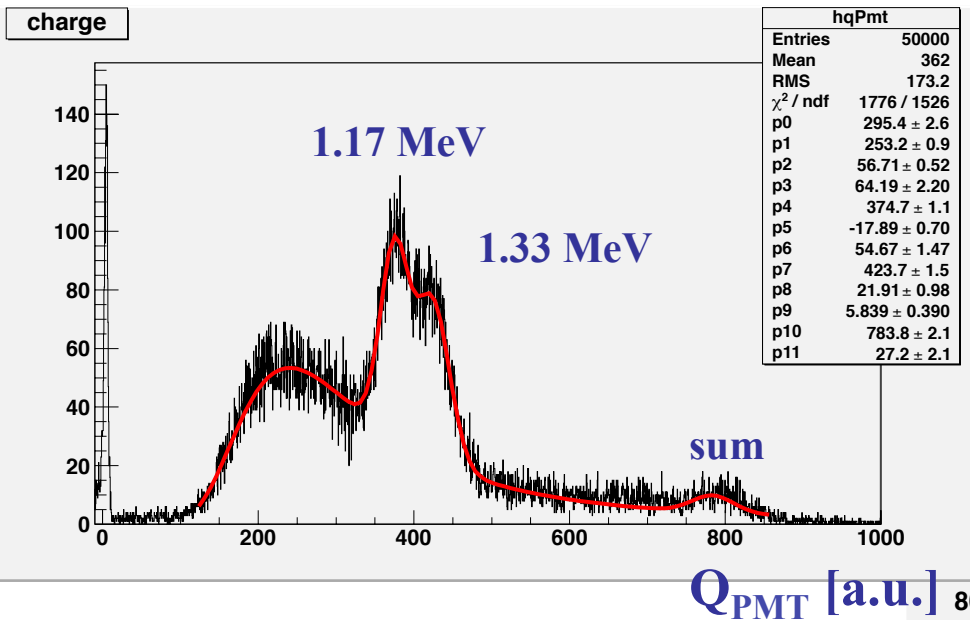


- The shaper is sensitive to the amplitude:
 \Rightarrow APD / PIN signal = maximum amplitude for $T > 6000$

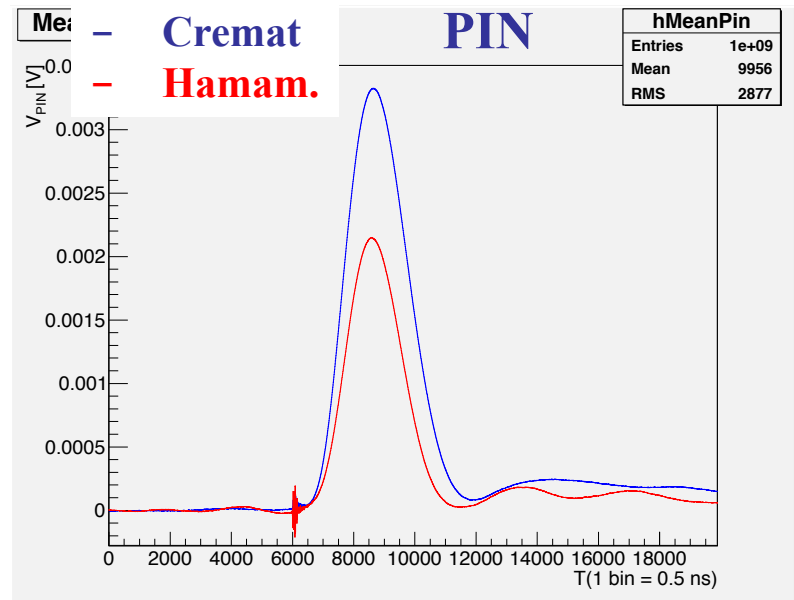
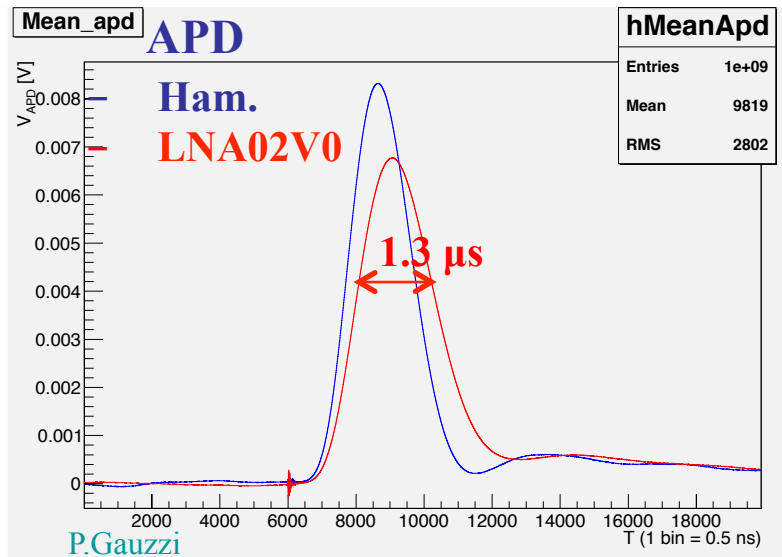
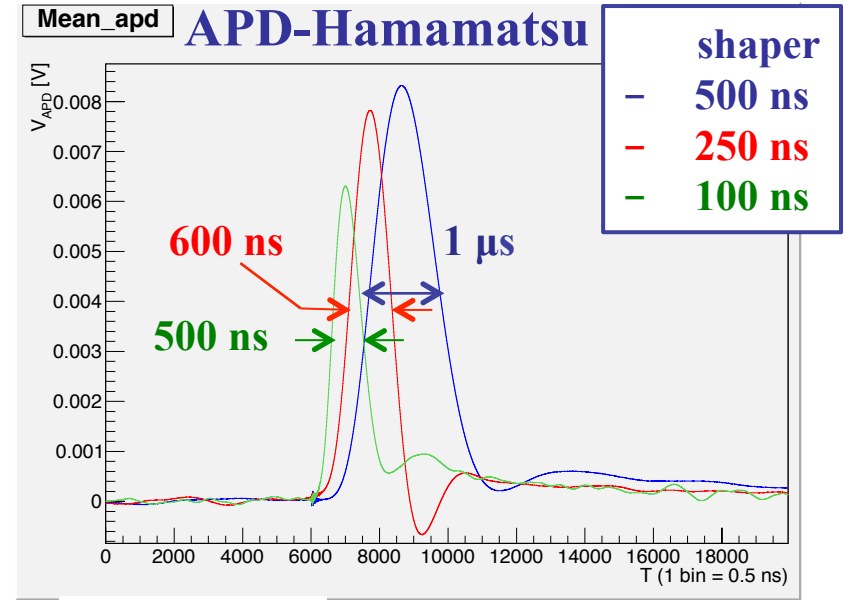
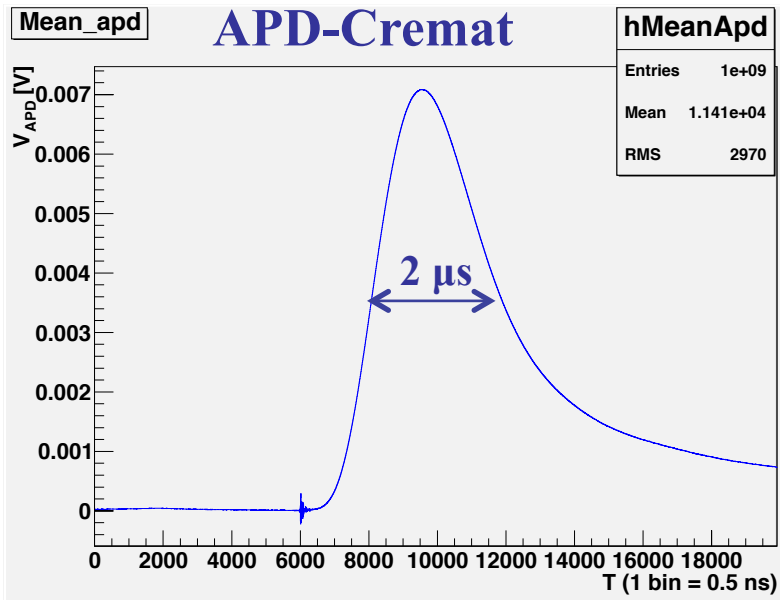
Configurations studied

- 1) **APD + CSP: Cremat i.t. 140 μ s + shaper 500 ns**
 - 2) **APD + CSP: Hamamatsu H4083, i.t. 100 ns + shaper 500 ns**
 - 3) **APD + CSP: Hamamatsu H4083 i.t. 100 ns + shaper 250 ns**
 - 4) **APD + CSP: Hamamatsu H4083 i.t. 100 ns + shaper 100 ns**
 - 5) **APD + CSP: LABE Rome-1 prototype (LNA02V0) i.t. 100 ns + shaper 500 ns**
 - 6) **PIN + CSP: Hamamatsu H4083 i.t. 100 ns + shaper 500 ns**
 - 7) **PIN + CSP: Cremat i.t. 140 μ s + shaper 500 ns**
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- **APD: 0.5 \times 0.5 cm² size, operated at 340 V and 380 V**
 - **PIN diode from BaBar: 1 \times 2 cm² size (only one of the two is readout), operated at 60 V**

^{60}Co spectrum with PMT



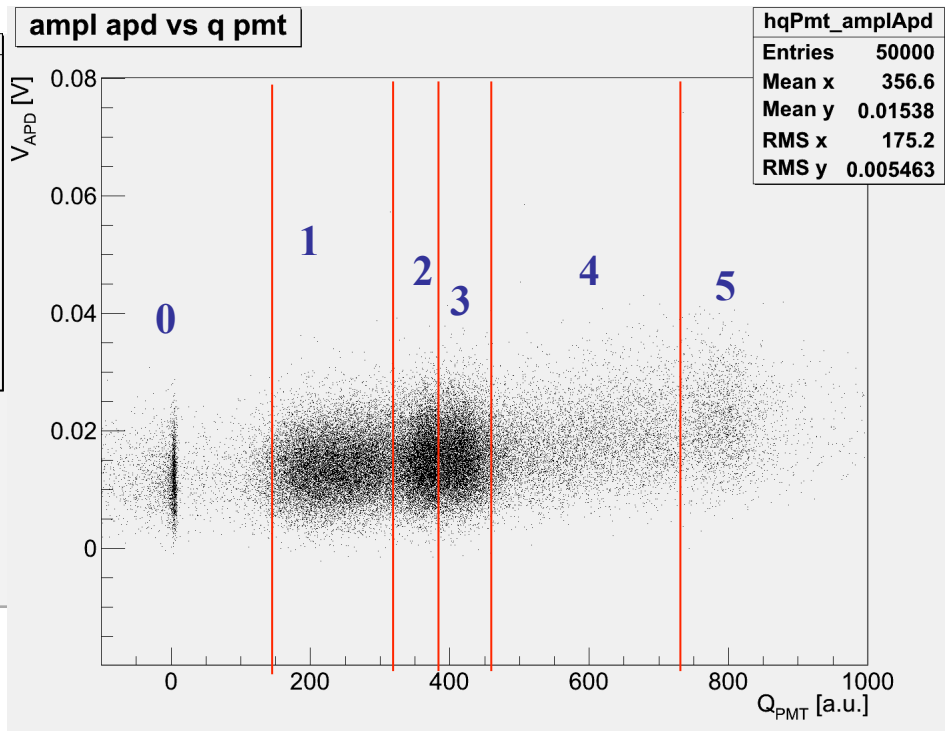
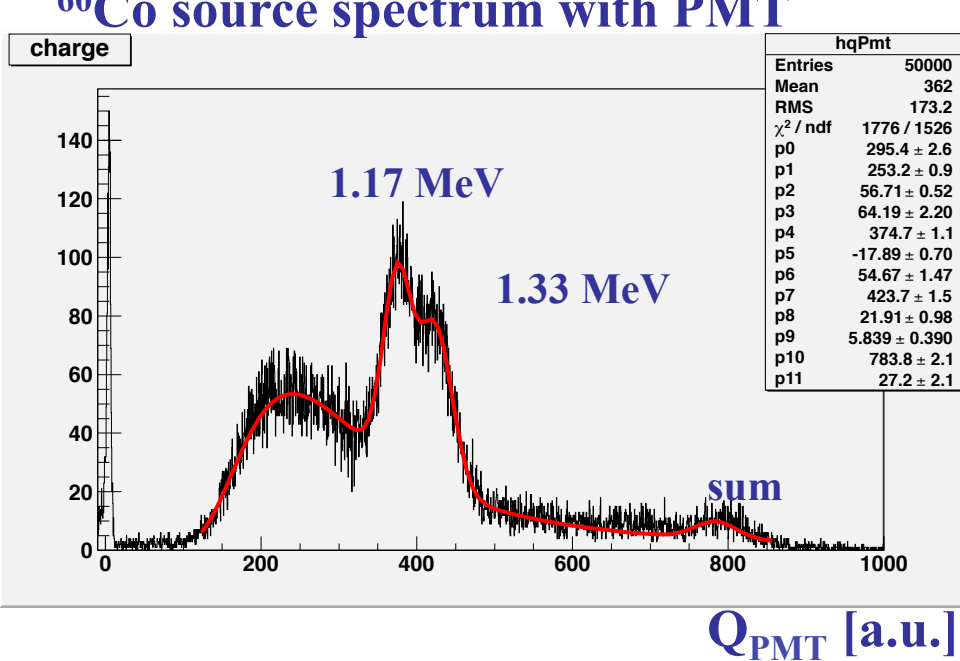
Average signals



Example: APD - CSP Hamam.

i.t. 100 ns – s.t. 500ns

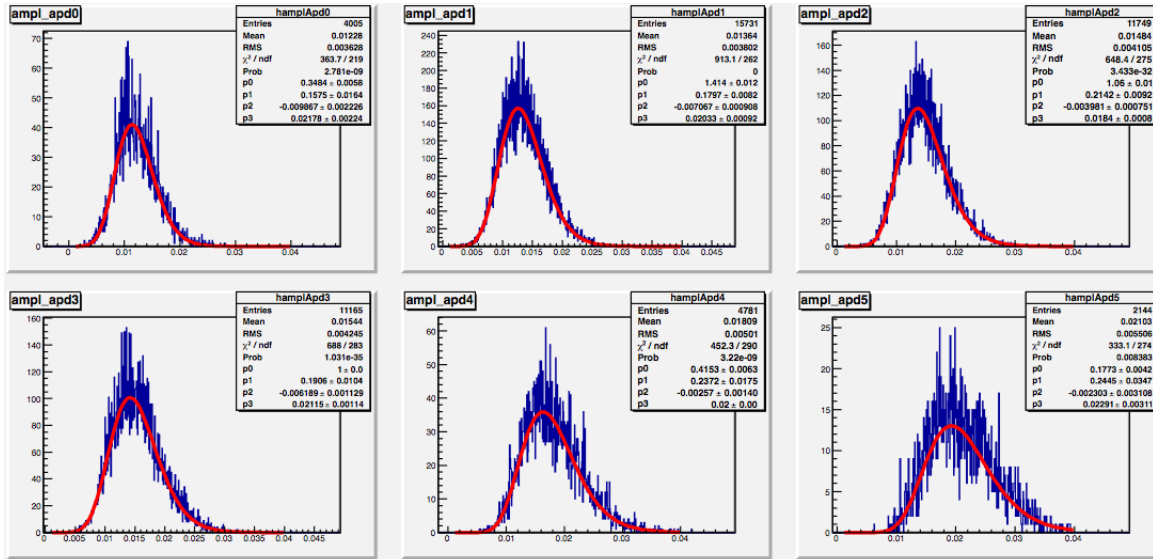
^{60}Co source spectrum with PMT



Divide into 6 regions:

- 0) pedestal
- 1) crystal bckg
- 2) 1.17 MeV peak
- 3) 1.33 MeV peak
- 4) tail of crystal bckg
- 5) sum 1.17 + 1.33 MeV

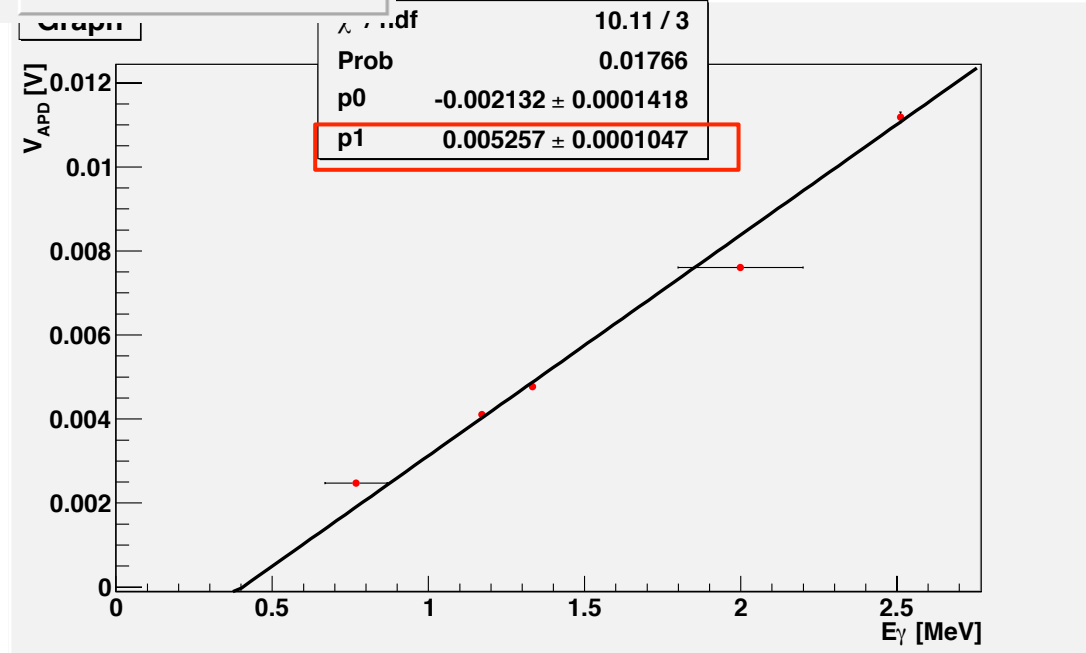
Energy scale



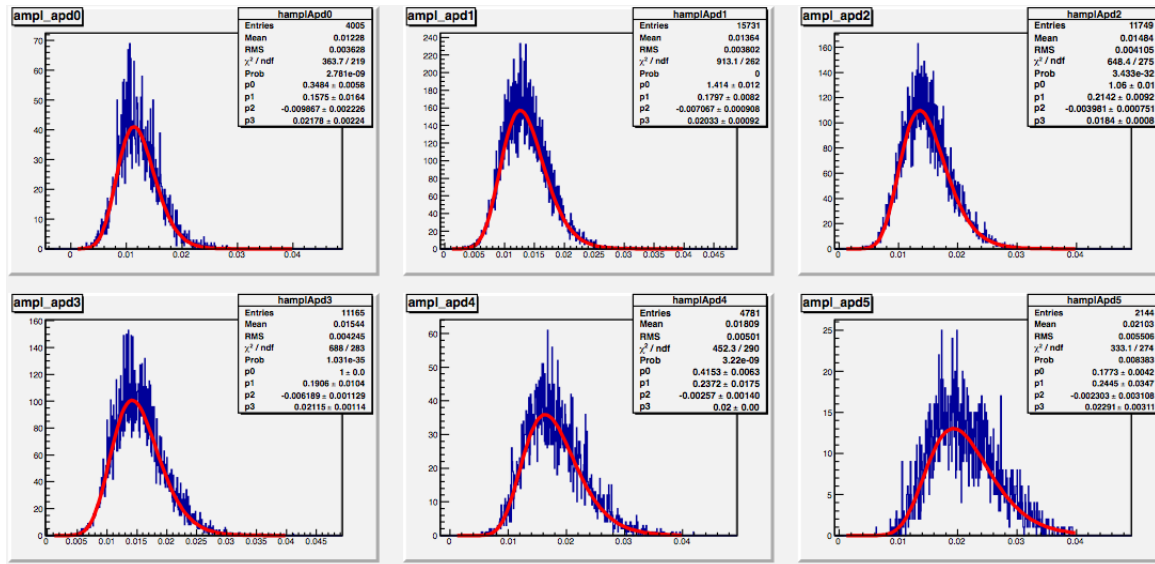
from the peaks of the distributions



the relevant parameter is p_1 [mV/MeV]



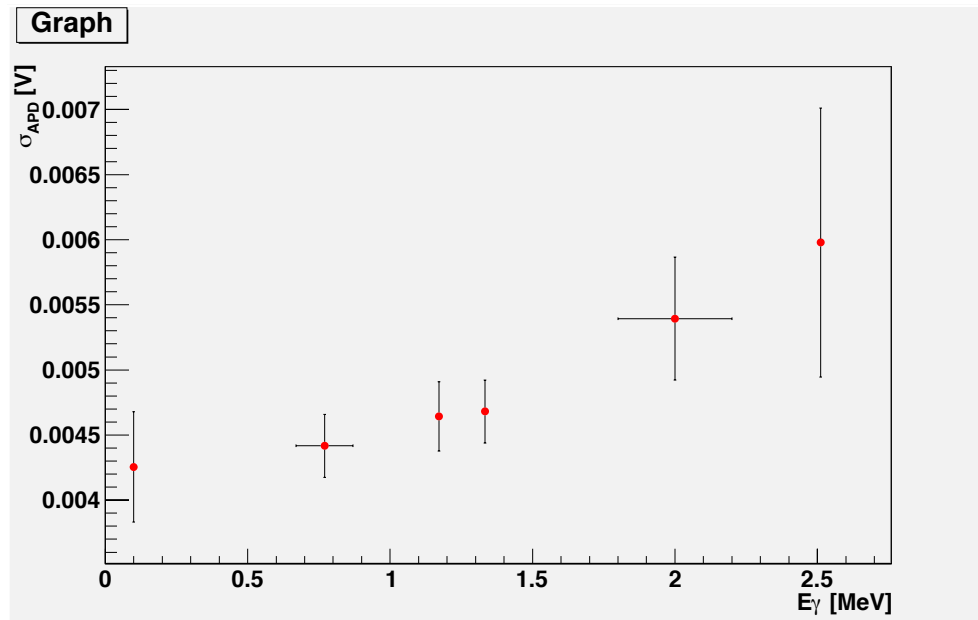
Noise evaluation



from the widths of the distributions



$$\frac{4.5 \text{ mV}}{5.3 \text{ mV/MeV}} = 0.85 \text{ MeV}$$

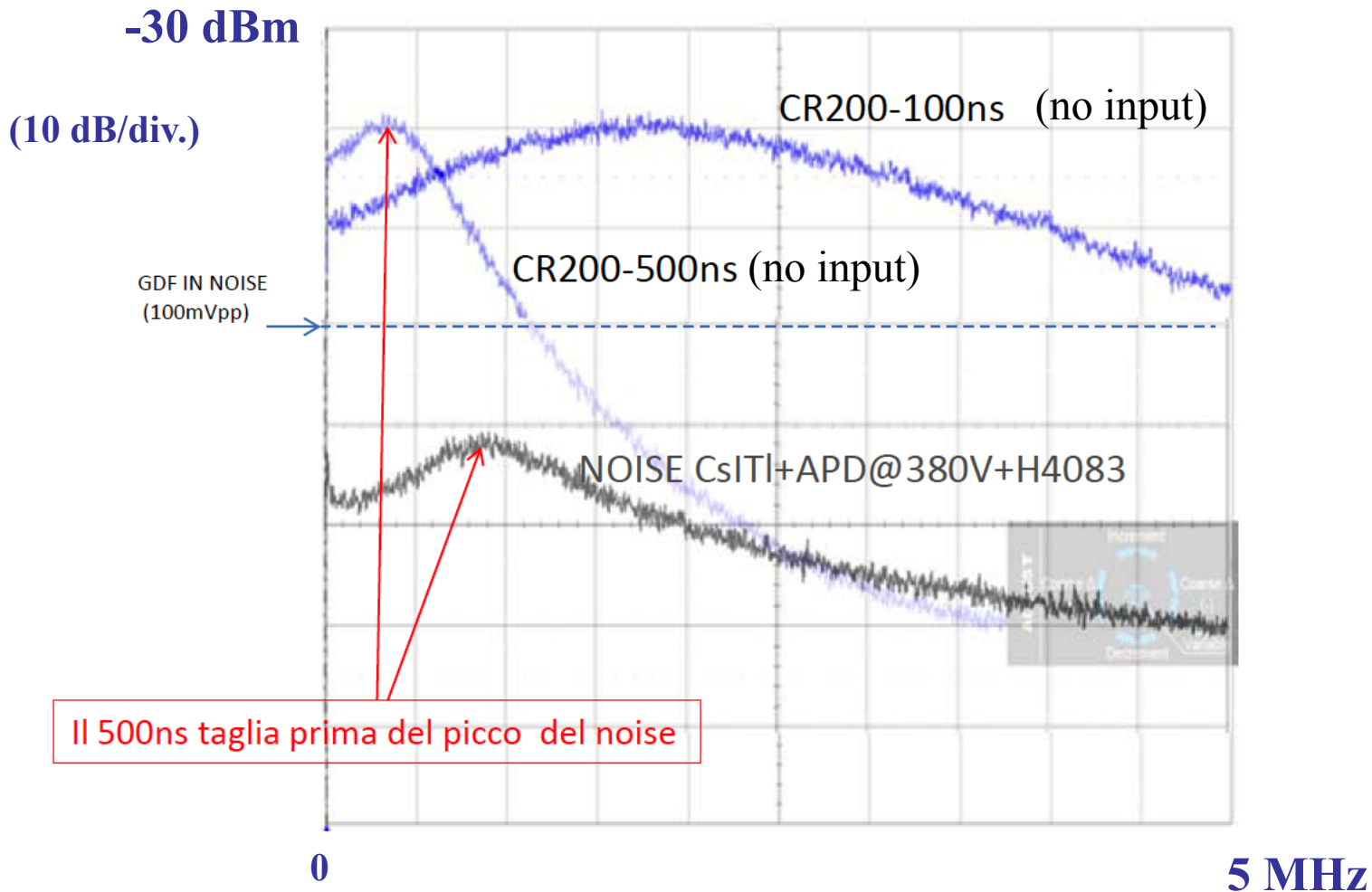


Noise in mV

Configuration	$V_{APD} = 340 \text{ V}$	$V_{APD} = 380 \text{ V}$	PIN
Cremat + sh. 500 ns	2.4	3.3	1.5
Hamamatsu + sh. 500 ns	2.9	4.5	2.5
Hamamatsu + sh. 250 ns	5.1	6.0	
Hamamatsu + sh. 100 ns	5.3	6.0	
proto. LNA02V0 + sh.500 ns		3.0	

- **The shaper at 500 ns has a narrower bandwidth w.r.t. 250 or 100 ns
⇒ lower noise**
- **LNA02V0 rise time ≈ 400 ns VS Hamamatsu H4083 ≈ 300 ns**

Frequency analysis



Energy calibration

p_1 [mV / MeV]

Config.	$V_{APD} = 340$ V	$V_{APD} = 380$ V	PIN
Cremat + sh. 500 ns	1.8	5.3	2.7
Hamamatsu + sh. 500 ns	2.3	5.3	1.1
Hamamatsu + sh. 250 ns	1.5	4.8	
Hamamatsu + sh. 100 ns	1.2	4.0	
proto. LNA02V0 + sh. 500 ns		5.3	

- **APD Gain(380 V) / Gain(340 V) \approx 3**
- **Signal amplitude decreases with the shaping time**

Noise [MeV]

Config.	$V_{APD} = 340 \text{ V}$	$V_{APD} = 380 \text{ V}$	PIN
Cremat + sh. 500 ns	1.3	0.62	0.56
Hamamatsu + sh. 500 ns	1.3	0.85	2.3
Hamamatsu + sh. 250 ns	3.4	1.3	
Hamamatsu + sh. 100 ns	4.4	1.5	
proto. LNA02V0 + sh. 500 ns		0.57	

- **APD:** electronic noise (in mV) is increasing from 340 V to 380 V, but signal/noise ratio is improving
- **PIN:** by reading both sensors we expect that signal/noise ratio decreases by a factor of $\sqrt{2}$ (0.4 and 1.5 MeV)

Conclusions

- **We tested a CsI(Tl) crystal with several configurations of readout electronics**
- **The shaper at 500 ns has a narrow bandwidth and cuts out the peak of the noise from sensor+amplifier chain, while at 100 ns the bandwidth is centered on the peak of sensor+amplifier**
- **Electronic noise is greater than 0.5 MeV**